



82963MGB  
Customer No. 01333

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:

John Border, et al

TECHNIQUE FOR MAKING DEEP  
MICROSTRUCTURES IN  
PHOTORESIST

Serial No. 09/993,033

Filed 06 November 2001

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA. 22313-1450

Sir:

Group Art Unit: 6479

Examiner: Kripa Sagar

I hereby certify that this correspondence is being  
deposited today with the United States Postal  
Service as first class mail in an envelope addressed  
to Commissioner For Patents, P.O. Box 1450,  
Alexandria, VA 22313-1450.

*Gina Marie Schmitt*  
Gina Marie Schmitt

*September 30 2003*  
Date

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TC 1700

**Amendment**

In response to the office action mailed July 31, 2003, please amend  
the above-identified application, without prejudice, as set forth below:

**Amendments to the Claims** are reflected in the listing of claims, which begins  
on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.